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1765

PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 1765**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Makoto IIDA et al.

Group Art Unit: 1765

Application No.: 09/869,912

Examiner: R. Kunemund

Filed: July 9, 2001

Docket No.: 110051

For: **SILICON SINGLE CRYSTAL WAFER AND PRODUCTION METHOD THEREOF
AND SOI WAFER**

**SUPPLEMENTAL RESPONSE AFTER
FINAL REJECTION UNDER 37 CFR §1.116**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

As a supplement to the Amendment After Final Rejection filed on October 14, 2003,
please further consider the following remarks.

Claims 13-33 are pending in this application.

I. Pending Claims 13-33 Define Patentable Subject Matter

The Office Action rejects claims 13-33 under 35 U.S.C. §103(a) over U.S. Patent
6,162,708 to Tamatsuka in view of Iida et al. (ELECTROCHEMICAL SOC'Y PROC., Vol. 99-1,
pp. 499-510). Applicants respectfully traverse this rejection.